

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:	)	Confirmation No.: 9528
Koichirto <b>TANAKA</b>	)	
Serial No. 10/769,820	)	Examiner: Samuel M. Heinrich
Filed: February 3, 2004	)	Group Art Unit: 3742
For: LASER IRRADIATION STAGE, LASER	)	Date: July 17, 2009
IRRADIATION OPTICAL SYSTEM,	)	
LASER IRRADIATION APPARATUS,	)	
LASER IRRADIATION METHOD, AND	)	
METHOD OF MANUFACTURING A	)	
SEMICONDUCTOR DEVICE	)	

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT UNDER 37 C.F.R. § 1.114**

In response to the Final Office Action mailed April 17, 2009, please amend the above-captioned application, as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks** follow the amendment section of this paper.